Yong-Kweon Kim

List of Publications by Year in Descending Order

173 papers	3,446 citations	31 h-index	51 g-index
226 ext. papers	3,849 ext. citations	3.3 avg, IF	4.69 L-index

#	Paper	IF	Citations
173	Microfluidic platform for cell analysis using through-polydimethylsiloxane micro-tip electrode array. *Microelectronic Engineering*, **2019**, 215, 111021	2.5	
172	Multi-wavelength light emitting diode-based disposable optrode array for in vivo optogenetic modulation. *Journal of Biophotonics*, **2019**, 12, e201800343	3.1	1
171	Disposable MEMS optrode array integrated with single LED for neurostimulation. *Sensors and Actuators A: Physical*, **2018**, 273, 276-284	3.9	5
170	Single-mask fabrication of micro-probe electrode array with various tip heights and sharpness using isotropic and anisotropic etching. *Micro and Nano Letters*, **2018**, 13, 1245-1247	0.9	5
169	Design and fabrication of a silicon-based MEMS acceleration switch working lower than 10 g. *Journal of Micromechanics and Microengineering*, **2017**, 27, 065009	2	6
168	Novel microbial photobioelectrochemical cell using an invasive ultramicroelectrode array and a microfluidic chamber. *Biotechnology Letters*, **2017**, 39, 849-855	3	8
167	Nanoslit-concentration-chip integrated microbead-based protein assay system for sensitive and quantitative detection. *RSC Advances*, **2017**, 7, 29679-29685	3.7	1
166	Chemical gating experiment of a nano-field-effect transistor sensor using the detection of negative ions in air. *Sensors and Actuators B: Chemical*, **2016**, 236, 654-658	8.5	4
165	Detecting ions in air using a nanofield-effect transistor (nanoFET). *Microelectronic Engineering*, **2016**, 158, 75-79	2.5	3
164	Silicon MEMS acceleration switch with high reliability using hooked latch. *Microelectronic Engineering*, **2016**, 152, 10-19	2.5	11
163	A 50–100 GHz ohmic contact SPDT RF MEMS silicon switch with dual axis movement. *Microelectronic Engineering*, **2016**, 162, 69-74	2.5	9
162	Direct identification of on-bead peptides using surface-enhanced Raman spectroscopic barcoding system for high-throughput bioanalysis. *Scientific Reports*, **2015**, 5, 10144	4.9	24
161	MEMS acceleration switch with bi-directionally tunable threshold. *Sensors and Actuators A: Physical*, **2014**, 208, 120-129	3.9	19
160	Nanoslit membrane-integrated fluidic chip for protein detection based on size-dependent particle trapping. *Lab on A Chip*, **2014**, 14, 237-43	7.2	7
159	Negative ions detection in air using nano field-effect-transistor (nanoFET). *Micro and Nano Systems Letters*, **2014**, 2,	2	4
158	Two-dimensional optical scanner with monolithically integrated glass microlens. *Journal of Micromechanics and Microengineering*, **2014**, 24, 055009	2	8
157	Suppression of surface crystallization on borosilicate glass using RF plasma treatment. *Applied Surface Science*, **2014**, 316, 484-490	6.7	3

156	Effect of reference electrode in the nanoFET (field-effect transistor)-based biosensor experiment. *Micro and Nano Letters*, **2014**, 9, 874-876	0.9	1
155	Deep wet etching of borosilicate glass and fused silica with dehydrated AZ4330 and a Cr/Au mask. *Journal of Micromechanics and Microengineering*, **2014**, 24, 015003	2	16
154	Wafer-Level Fabrication of a Fused-Quartz Double-Ended Tuning Fork Resonator Oscillator Using Quartz-on-Quartz Direct Bonding. *IEEE Electron Device Letters*, **2013**, 34, 692-694	4.4	8
153	Monolithically integrated glass microlens scanner using a thermal reflow process. *Journal of Micromechanics and Microengineering*, **2013**, 23, 065012	2	6
152	Electrochemical sensing of high density photosynthetic cells using a microfluidic chip. *Sensors and Actuators B: Chemical*, **2013**, 188, 1300-1305	8.5	10
151	A Miniaturized Broadband Multi-State Reflectometer Integrated on a Silicon MEMS Probe for Complex Permittivity Measurement of Biological Material. *IEEE Transactions on Microwave Theory and Techniques*, **2013**, 61, 2205-2214	4.1	25
150	Conductive microtip electrode array with variable aspect ratio using combination process of reactive ion etching. *Journal of Micromechanics and Microengineering*, **2013**, 23, 115009	2	4
149	A Ku-band miniaturized microwave ablation system integrated on a micromachined silicon applicator **2013**,		1
148	Thermal de-isolation of silicon microstructures in a plasma etching environment. *Journal of Micromechanics and Microengineering*, **2013**, 23, 025026	2	9
147	A wafer-level vacuum package using glass-reflowed silicon through-wafer interconnection for nano/micro devices. *Journal of Nanoscience and Nanotechnology*, **2012**, 12, 5252-62	1.3	10
146	Design of etch holes to compensate spring width loss for reliable resonant frequencies. *Journal of Micromechanics and Microengineering*, **2012**, 22, 057002	2	1
145	Bead affinity chromatography in a temperature-controllable microsystem for biomarker detection. *Analytical and Bioanalytical Chemistry*, **2012**, 404, 2267-75	4.4	19
144	RF MEMS suspended band-stop resonator and filter for frequency and bandwidth continuous fine tuning. *Journal of Micromechanics and Microengineering*, **2012**, 22, 015005	2	3
143	Controlled volume transfer and lens shape formation by liquid bridge disconnection. *Applied Physics Letters*, **2012**, 100, 214103	3.4	3
142	Fabrication of a vertical sidewall using double-sided anisotropic etching of <1 0 0> oriented silicon. *Journal of Micromechanics and Microengineering*, **2012**, 22, 095014	2	14
141	Surface-enhanced Raman scattering-active nanostructures and strategies for bioassays. *Nanomedicine*, **2011**, 6, 1463-80	5.6	108
140	. *IEEE Transactions on Industrial Electronics*, **2011**, 58, 4830-4836	8.9	9
139	Feed-through capacitance reduction for a micro-resonator with push-pull configuration based on electrical characteristic analysis of resonator with direct drive. *Sensors and Actuators A: Physical*, **2011**, 170, 131-138	3.9	17

138	Two-state reconfigurable miniaturized low-pass filter using micromachined double-contact RF switches. *Sensors and Actuators A: Physical*, **2011**, 170, 172-179	3.9	0
137	Fabrication of polydimethylsiloxane microlens arrays by surface tension induced liquid separation. *Micro and Nano Letters*, **2011**, 6, 809	0.9	3
136	Design, fabrication and characterization of piezoelectric micro-cantilever operated in liquid environment for ultrasound energy source applications. *Microsystem Technologies*, **2011**, 17, 1319-1327	1.7	2
135	MEMS-tunable composite right/left-handed (CRLH) transmission line and its application to a phase shifter. *Journal of Micromechanics and Microengineering*, **2011**, 21, 125022	2	2
134	Numerical analysis and demonstration of a 2-DOF large-size micromirror with sloped electrodes. *Journal of Micromechanics and Microengineering*, **2011**, 21, 095006	2	6
133	Electrostatically driven low-voltage micromechanical RF switches using robust single-crystal silicon actuators. *Journal of Micromechanics and Microengineering*, **2010**, 20, 095007	2	17
132	Automated maskless photolithography system for peptide microarray synthesis on a chip. *ACS Combinatorial Science*, **2010**, 12, 463-71		24
131	Tunable composite right/left-handed transmission line with positive/negative phase tunability using integrated MEMS switches **2010**,		1
130	LTCC-based vertical via interconnects for RF MEMS packaging. *Microwave and Optical Technology Letters*, **2010**, 52, 252-257	1.2	3
129	Multifunctional silver-embedded magnetic nanoparticles as SERS nanoprobes and their applications. *Small*, **2010**, 6, 119-25	11	161
128	A high-temperature MEMS heater using suspended silicon structures. *Journal of Micromechanics and Microengineering*, **2009**, 19, 115011	2	31
127	New release technique of a thick sacrificial layer and residue effects on novel half-coaxial transmission line filters. *Journal of Micromechanics and Microengineering*, **2009**, 19, 055018	2	2
126	Pull-in voltage uniformity analysis of digitally operated micro mirror array with torsional springs. *Journal of Micromechanics and Microengineering*, **2009**, 19, 035006	2	3
125	Design and fabrication of a self-aligned parallel-plate-type silicon micromirror minimizing the effect of misalignment. *Journal of Micromechanics and Microengineering*, **2009**, 19, 055004	2	1
124	Magnetic surface-enhanced Raman spectroscopic (M-SERS) dots for the identification of bronchioalveolar stem cells in normal and lung cancer mice. *Biomaterials*, **2009**, 30, 3915-25	15.6	53
123	Protein separation and identification using magnetic beads encoded with surface-enhanced Raman spectroscopy. *Analytical Biochemistry*, **2009**, 391, 24-30	3.1	59
122	MEMS micromirror characterization in space environments. *Optics Express*, **2009**, 17, 3370-80	3.3	14
121	Switchable Composite Right/Left-Handed (S-CRLH) Transmission Line Using MEMS Switches. *IEEE Microwave and Wireless Components Letters*, **2009**, 19, 804-806	2.6	7

120	An absorptive single-pole four-throw switch using multiple-contact MEMS switches and its application to a monolithic millimeter-wave beam-forming network. *Journal of Micromechanics and Microengineering*, **2009**, 19, 015024	2	4
119	Fabrication of a Bottom Electrode for a Nano-scale Beam Resonator Using Backside Exposure with a Self-aligned Metal Mask. *Journal of Electrical Engineering and Technology*, **2009**, 4, 546-551	1.4	2
118	Silicon/quartz bonding and quartz deep RIE for the fabrication of quartz resonator structures **2008**,		2
117	A single-pole nine-throw antenna switch using radio-frequency microelectromechanical systems technology for broadband multi-mode and multi-band front-ends. *Journal of Micromechanics and Microengineering*, **2008**, 18, 015012	2	9
116	A low-drift, open-loop controlled, single crystalline silicon micromirror with floating field-limiting shields. *Journal of Micromechanics and Microengineering*, **2008**, 18, 035031	2	5
115	A hybrid RF MEMS probe array system with a SP3T RF MEMS silicon switch for permittivity measurement. *Journal of Micromechanics and Microengineering*, **2008**, 18, 085006	2	12
114	Monolithic reconfigurable bandpass filter using single-pole double-throw RF MEMS switches. *IEICE Electronics Express*, **2008**, 5, 483-489	0.5	2
113	Cold- and hot-switching lifetime characterizations of ohmic-contact RF MEMS switches. *IEICE Electronics Express*, **2008**, 5, 418-423	0.5	8
112	An integrated microfluidic chip for the analysis of biochemical reactions by MALDI mass spectrometry. *Biomedical Microdevices*, **2008**, 10, 1-9	3.7	15
111	Novel MMIC protection technique in plasma etching process for mechanically movable RF mems antenna. *Microwave and Optical Technology Letters*, **2008**, 50, 3089-3093	1.2	
110	A method of binding kinetics of a ligand to micropatterned proteins on a microfluidic chip. *Biosensors and Bioelectronics*, **2007**, 22, 891-8	11.8	8
109	Light-directed synthesis of peptide nucleic acids (PNAs) chips. *Biosensors and Bioelectronics*, **2007**, 22, 2891-7	11.8	24
108	Planar type micromachined probe with low uncertainty at low frequencies. *Sensors and Actuators A: Physical*, **2007**, 139, 111-117	3.9	9
107	Fabrication and Characterization of RF MEMS Package Based on LTCC Lid Substrate and Gold-Tin Eutectic Bonding **2007**,		6
106	Multiplex targeting, tracking, and imaging of apoptosis by fluorescent surface enhanced Raman spectroscopic dots. *Bioconjugate Chemistry*, **2007**, 18, 1155-62	6.3	79
105	Surface-enhanced Raman spectroscopic-encoded beads for multiplex immunoassay. *ACS Combinatorial Science*, **2007**, 9, 237-44		81
104	Improvement of Maskless Photolithography of Bio Pattern with Single Crystalline Silicon Micromirror Array. *Journal of Electrical Engineering and Technology*, **2007**, 2, 274-279	1.4	2
103	Biochemical reactions on a microfluidic chip based on a precise fluidic handling method at the nanoliter scale. *Biotechnology and Bioprocess Engineering*, **2006**, 11, 146-153	3.1	10

102	Fabrication of disposable protein chip for simultaneous sample detection. *Biotechnology and Bioprocess Engineering*, **2006**, 11, 455-461	3.1	6
101	Novel compact low-loss millimeter-wave filters using micromachined overlay and inverted overlay coplanar waveguide transmission lines with defected ground structures. *Journal of Micromechanics and Microengineering*, **2006**, 16, 2183-2191	2	5
100	V-band Single-Platform Beam Steering Transmitters Using Micromachining Technology **2006**,		3
99	Application of a temperature-controllable microreactor to simple and rapid protein identification using MALDI-TOF MS. *Lab on A Chip*, **2006**, 6, 1056-61	7.2	13
98	MEMS-based compact dual-band bandpass filters with applications to wireless local area network. *Journal of Micromechanics and Microengineering*, **2006**, 16, 1135-1142	2	3
97	Packaging for RF MEMS devices using LTCC substrate and BCB adhesive layer. *Journal of Micromechanics and Microengineering*, **2006**, 16, 150-156	2	39
96	A Planar High-Q Micromachined Monolithic Half-Coaxial Transmission-Line Filter. *IEEE Transactions on Microwave Theory and Techniques*, **2006**, 54, 4161-4168	4.1	13
95	Nanoparticle probes with surface enhanced Raman spectroscopic tags for cellular cancer targeting. *Analytical Chemistry*, **2006**, 78, 6967-73	7.8	243
94	Biochip fluorescence detection system with spatial and spectral separation. *Optics and Lasers in Engineering*, **2006**, 44, 1198-1208	4.6	1
93	Characterization of a single-crystal silicon micromirror array for maskless UV lithography in biochip applications. *Journal of Micromechanics and Microengineering*, **2006**, 16, 2360-2368	2	9
92	Direct nanomechanical machining of gold nanowires using a nanoindenter and an atomic force microscope. *Journal of Micromechanics and Microengineering*, **2005**, 15, 551-556	2	49
91	Millimeter-wave MEMS tunable low pass filter with reconfigurable series inductors and capacitive shunt switches. *IEEE Microwave and Wireless Components Letters*, **2005**, 15, 691-693	2.6	23
90	A mechanically reliable digital-type single crystalline silicon (SCS) RF MEMS variable capacitor. *Journal of Micromechanics and Microengineering*, **2005**, 15, 1854-1863	2	6
89	Permittivity measurements up to 30 GHz using micromachined probe. *Journal of Micromechanics and Microengineering*, **2005**, 15, 543-550	2	26
88	Reconfigurable millimeter-wave filters using CPW-based periodic structures with novel multiple-contact MEMS switches. *Journal of Microelectromechanical Systems*, **2005**, 14, 456-463	2.5	19
87	Measurement of the mechanical properties of electroplated gold thin films using micromachined beam structures. *Sensors and Actuators A: Physical*, **2005**, 117, 17-27	3.9	105
86	Microfluidic chip for biochemical reaction and electrophoretic separation by quantitative volume control. *Sensors and Actuators B: Chemical*, **2005**, 110, 164-173	8.5	24
85	Synthesis of photolabile o-nitroveratryloxycarbonyl (NVOC) protected peptide nucleic acid monomers. *Tetrahedron*, **2005**, 61, 7967-7973	2.4	18

84	Bias-free pneumatic sample injection in microchip electrophoresis. *Journal of Chromatography A*, **2005**, 1063, 253-6	4.5	16
83	Novel low-cost planar probes with broadside apertures for nondestructive dielectric measurement of biological materials at microwave frequencies. *IEEE Transactions on Microwave Theory and Techniques*, **2005**, 53, 134-143	4.1	26
82	In vitro and in vivo measurement for biological applications using micromachined probe. *IEEE Transactions on Microwave Theory and Techniques*, **2005**, 53, 3415-3421	4.1	13
81	Microaffinity purification of proteins based on photolytic elution: toward an efficient microbead affinity chromatography on a chip. *Electrophoresis*, **2005**, 26, 694-702	3.6	33
80	Fabrication of microchip electrophoresis devices and effects of channel surface properties on separation efficiency. *Sensors and Actuators B: Chemical*, **2005**, 107, 818-824	8.5	34
79	Enhancement of analyte ionization in desoprtion/ionization on porous silicon (DIOS)-mass spectrometry (MS). *Biotechnology and Bioprocess Engineering*, **2005**, 10, 212-217	3.1	4
78	Monolithic fabrication of optical benches and scanning mirror using silicon bulk micromachining. *Journal of Micromechanics and Microengineering*, **2005**, 15, 747-755	2	6
77	Silicon MEMS probe using a simple adhesive bonding process for permittivity measurement. *Journal of Micromechanics and Microengineering*, **2005**, 15, N11-N16	2	2
76	MEMS variable optical attenuator using a translation motion of 45□tilted vertical mirror. *Journal of Micromechanics and Microengineering*, **2005**, 15, 1466-1475	2	17
75	Prevention method of a notching caused by surface charging in silicon reactive ion etching. *Journal of Micromechanics and Microengineering*, **2005**, 15, 358-361	2	30
74	Silicon scanning mirror of two DOF with compensation current routing. *Journal of Micromechanics and Microengineering*, **2004**, 14, 1455-1461	2	22
73	The SiOG-based single-crystalline silicon (SCS) RF MEMS switch with uniform characteristics. *Journal of Microelectromechanical Systems*, **2004**, 13, 1036-1042	2.5	50
72	Microbead-based affinity chromatography chip using RNA aptamer modified with photocleavable linker. *Electrophoresis*, **2004**, 25, 3730-9	3.6	53
71	Chemical mechanical polishing by colloidal silica-based slurry for micro-scratch reduction. *Wear*, **2004**, 257, 785-789	3.5	70
70	Micro protein patterning using a lift-off process with fluorocarbon thin film. *Sensors and Actuators B: Chemical*, **2004**, 99, 623-632	8.5	36
69	On-line sample cleanup and chiral separation of gemifloxacin in a urinary solution using chiral crown ether as a chiral selector in microchip electrophoresis. *Journal of Chromatography A*, **2004**, 1055, 241-5	4.5	45
68	Effects of polymer grafting on a glass surface for protein chip applications. *Colloids and Surfaces B: Biointerfaces*, **2004**, 33, 67-75	6	41
67	A compact low-loss reconfigurable monolithic low-pass filter using multiple-contact MEMS switches. *IEEE Microwave and Wireless Components Letters*, **2004**, 14, 37-39	2.6	12

66	Low-loss analog and digital reflection-type MEMS phase shifters with 1:3 bandwidth. *IEEE Transactions on Microwave Theory and Techniques*, **2004**, 52, 211-219	4.1	25
65	Design, fabrication and characterization of an electromagnetically actuated addressable out-of-plane micromirror array for vertical optical source applications. *Journal of Micromechanics and Microengineering*, **2003**, 13, 853-863	2	7
64	Electric spring modeling for a comb actuator deformed by the footing effect in deep reactive ion etching. *Journal of Micromechanics and Microengineering*, **2003**, 13, 72-79	2	7
63	Micromirror array for protein micro array fabrication. *Journal of Micromechanics and Microengineering*, **2003**, 13, 474-481	2	15
62	Multi-step reactions on microchip platform using nitrocellulose membrane reactor. *Biotechnology and Bioprocess Engineering*, **2003**, 8, 257-262	3.1	9
61	Integration of on-column immobilized enzyme reactor in microchip electrophoresis. *Electrophoresis*, **2003**, 24, 200-6	3.6	33
60	Effect of mechanical process parameters on chemical mechanical polishing of Al thin films. *Microelectronic Engineering*, **2003**, 65, 13-23	2.5	23
59	Mechanical characterization of micro/nanoscale structures for MEMS/NEMS applications using nanoindentation techniques. *Ultramicroscopy*, **2003**, 97, 481-94	3.1	255
58	Protein patterning on silicon-based surface using background hydrophobic thin film. *Biosensors and Bioelectronics*, **2003**, 18, 437-44	11.8	69
57	Protein patterning by maskless photolithography on hydrophilic polymer-grafted surface. *Biosensors and Bioelectronics*, **2003**, 19, 485-94	11.8	39
56	Protein patterning by virtual mask photolithography using a micromirror array. *Journal of Micromechanics and Microengineering*, **2003**, 13, 18-25	2	29
55	Quantitatively controlled nanoliter liquid manipulation using hydrophobic valving and control of surface wettability. *Journal of Micromechanics and Microengineering*, **2003**, 13, 89-97	2	28
54	Electromagnetic micromirror array with single-crystal silicon mirror plate and aluminum spring. *Journal of Lightwave Technology*, **2003**, 21, 584-590	4	20
53	A V-band micromachined 2-D beam-steering antenna driven by magnetic force with polymer-based hinges. *IEEE Transactions on Microwave Theory and Techniques*, **2003**, 51, 325-331	4.1	34
52	Silicon micro XY-stage with a large area shuttle and no-etching holes for SPM-based data storage. *Journal of Microelectromechanical Systems*, **2003**, 12, 470-478	2.5	52
51	V-band 2-b and 4-b low-loss and low-voltage distributed MEMS digital phase shifter using metal-air-metal capacitors. *IEEE Transactions on Microwave Theory and Techniques*, **2002**, 50, 2918-2923	4.1	55
50	Chiral separation of gemifloxacin in sodium-containing media using chiral crown ether as a chiral selector by capillary and microchip electrophoresis. *Electrophoresis*, **2002**, 23, 972-7	3.6	43
49	Low-loss and compact V-band MEMS-based analog tunable bandpass filters. *IEEE Microwave and Wireless Components Letters*, **2002**, 12, 432-434	2.6	48

48	V-band reflection-type phase shifters using micromachined CPW coupler and RF switches. *Journal of Microelectromechanical Systems*, **2002**, 11, 808-814	2.5	21
47	Continuous anti-stiction coatings using self-assembled monolayers for gold microstructures. *Journal of Micromechanics and Microengineering*, **2002**, 12, 688-695	2	20
46	A compact V-band 2-bit reflection-type MEMS phase shifter. *IEEE Microwave and Wireless Components Letters*, **2002**, 12, 324-326	2.6	21
45	A high-aspect-ratio comb actuator using UV-LIGA surface micromachining and (110) silicon bulk micromachining. *Journal of Micromechanics and Microengineering*, **2002**, 12, 128-135	2	29
44	Micro XY-stage using silicon on a glass substrate. *Journal of Micromechanics and Microengineering*, **2002**, 12, 103-107	2	43
43	Removal of Sodium Ion and Chiral Analysis Using Crown Ether as a Chiral Selector in Microchip Electrophoresis **2002**, 575-577		
42	A new micromachined overlay CPW structure with low attenuation over wide impedance ranges and its application to low-pass filters. *IEEE Transactions on Microwave Theory and Techniques*, **2001**, 49, 1634-1639	4.1	27
41	Low-loss analog and digital micromachined impedance tuners at the Ka-band. *IEEE Transactions on Microwave Theory and Techniques*, **2001**, 49, 2394-2400	4.1	40
40	Compact low-loss monolithic CPW filters using air-gap overlay structures. *IEEE Microwave and Wireless Components Letters*, **2001**, 11, 328-330	2.6	4
39	Low-loss micromachined inverted overlay CPW lines with wide impedance ranges and inherent airbridge connection capability. *IEEE Microwave and Wireless Components Letters*, **2001**, 11, 59-61	2.6	20
38	Tunable millimeter-wave filters using a coplanar waveguide and micromachined variable capacitors. *Journal of Micromechanics and Microengineering*, **2001**, 11, 706-712	2	28
37	Fabrication of Micro XY-Stage with Large-Area Rectangular Shuttle using Anodic Bonding Process **2001**, 752-755		1
36	Fabrication and Experiments on Electromagnetic Micromirror Array with Bulk Silicon Mirror Plate and Aluminum Spring **2001**, 1292-1295		
35	A 3-Voltage Actuated Micromachined RF Switch for Telecommunications Applications **2001**, 1512-1515		1
34	Novel Micromachined Coplanar Waveguide Transmission Lines for Application in Millimeter-Wave Circuits. *Japanese Journal of Applied Physics*, **2000**, 39, 7120-7124	1.4	13
33	A Surface-Bulk-Micromachined Electromagnetic Gyroscope Operating at Atmospheric Pressure. *Japanese Journal of Applied Physics*, **2000**, 39, 7130-7133	1.4	7
32	Design and Fabrication of Electromagnetic Micromirror with Bulk Silicon Mirror Plate and Aluminum Spring. *Japanese Journal of Applied Physics*, **2000**, 39, 7138-7141	1.4	4
31	Design and fabrication of 10□10 micro-spatial light modulator array for phase and amplitude modulation. *Sensors and Actuators A: Physical*, **1999**, 78, 63-70	3.9	25

30	Fabrication and experimentation of vertical spring-type micromirror using shielding screen structure. *IEEE Journal of Selected Topics in Quantum Electronics*, **1999**, 5, 102-105	3.8	1
29	Mechanical Property Measurement of Electroplated Gold Microstructure Using Resonance Method. *Materials Research Society Symposia Proceedings*, **1999**, 605, 229		7
28	A planar vibratory gyroscope using electromagnetic force. *Sensors and Actuators A: Physical*, **1998**, 65, 101-108	3.9	5
27	Design and fabrication of micromirror array supported by vertical springs. *Sensors and Actuators A: Physical*, **1998**, 66, 144-149	3.9	16
26	Fabrication and experiment of a planar micro ion drag pump. *Sensors and Actuators A: Physical*, **1998** , 70, 1-5	3.9	65
25	Measurements of a fabricated micro mirror using a lateral-effect position-sensitive photodiode. *IEEE Transactions on Industrial Electronics*, **1998**, 45, 861-865	8.9	5
24	The Surface Modification with Fluorocarbon Thin Films for the Prevention of Stiction in Mems. *Materials Research Society Symposia Proceedings*, **1998**, 518, 143		5
23	Novel Fabrication Process of Freestanding Metallic Microstructures Using Double Electroplating. *Japanese Journal of Applied Physics*, **1998**, 37, 7104-7109	1.4	4
22	Novel Fabrication of Comb Actuator Using Reactive Ion Etching of Polysilicon and (110) Si Anisotropic Bulk Etching in KOH. *Japanese Journal of Applied Physics*, **1998**, 37, 7086-7092	1.4	3
21	Fabrication and Experiment of Planar Micro Ion Drag Pump. *IEEJ Transactions on Sensors and Micromachines*, **1998**, 118, 255-259	0.2	
20	Design and fabrication of hidden-spring-structure-type micro-SLM for phase and amplitude modulation **1998**,		4
19	Anisotropic Bulk Etching of (110) Silicon with High Aspect Ratio. *IEEJ Transactions on Sensors and Micromachines*, **1998**, 118, 32-36	0.2	6
18	Fabrication and Experiment of Novel Type Electrohydrodynamic Micropump.. *IEEJ Transactions on Sensors and Micromachines*, **1997**, 117, 170-174	0.2	3
17	Design and fabrication of micromirror supported by electroplated nickel posts. *Sensors and Actuators A: Physical*, **1996**, 54, 464-467	3.9	28
16	Fabrication and experiment of planar micro ion drag pump		4
15	[110] silicon etching for high aspect ratio comb structures		1
14	Two-mass system with wide bandwidth for SiOG (silicon on glass) vibratory gyroscopes		4
13	A micromachined monolithic half coaxial transmission line filter		1

List of Publications

12	Multi-layer processed probes for permittivity measurement	2
11	A 5-17 GHz wideband reflection-type phase shifter using digitally operated capacitive MEMS switches	1
10	A V-band CPS distributed analog MEMS phase shifter	1
9	A 15-to-45 GHz low-loss analog reflection-type MEMS phase shifter	1
8	Vacuum packaged low noise gyroscope with sub mdeg/s//spl radic/Hz resolution	1
7	A few deg/hr resolvable low noise lateral microgyroscope	2
6	Protein patterning by virtual mask photolithography using micromirror array	1
5	Design and fabrication of electromagnetic micromirror with bulk silicon mirror plate and aluminum spring	2
4	Micromachined frequency-variable impedance tuners using resonant unit cells	3
3	Millimeter-wave micromachined tunable filters	1
2	Design And Fabrication Of Micro Mirror Supported By Electroplated Nickel Posts	2
1	Micro electrohydrodynamic pump driven by traveling electric fields	3